

# Optimizing Solution Chemistry for Reduced Damage during CMP

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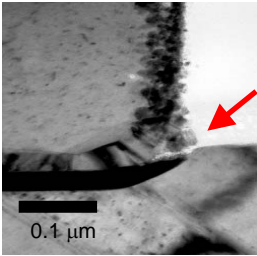
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<sup>3</sup>JSR Corporation, Yokkaichi Research Center, 100 Kawajiri-cho, Yokkaichi, Japan



# Evolution of Defects control Yield through Processing

- Lower driving force for cracking,  $G_{total}$

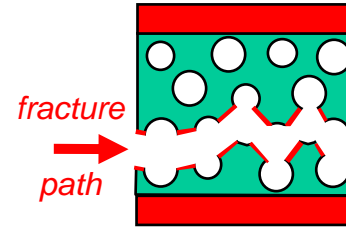
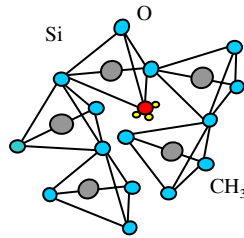


nano-scale defect

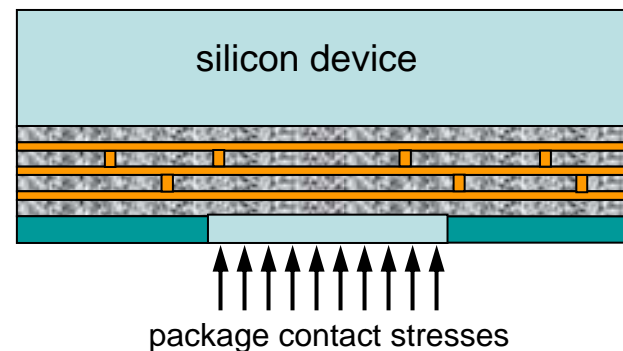
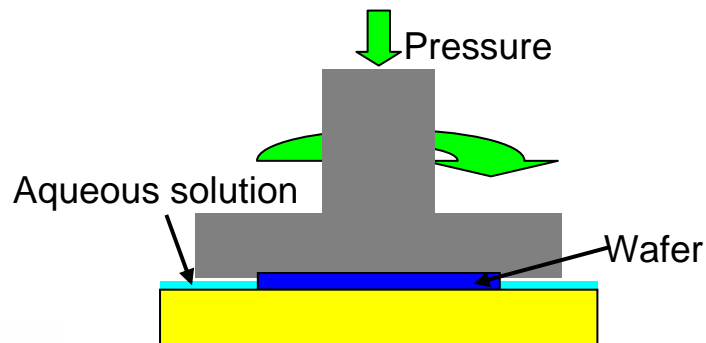
- thin film stresses
- CMP stresses

$$G_{total} \leq G_c \text{ (J / m}^2\text{)}$$

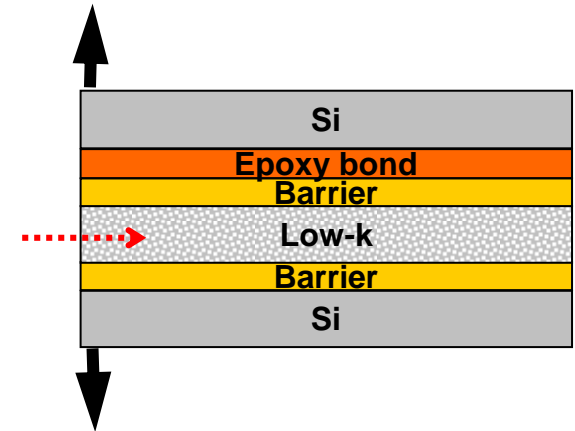
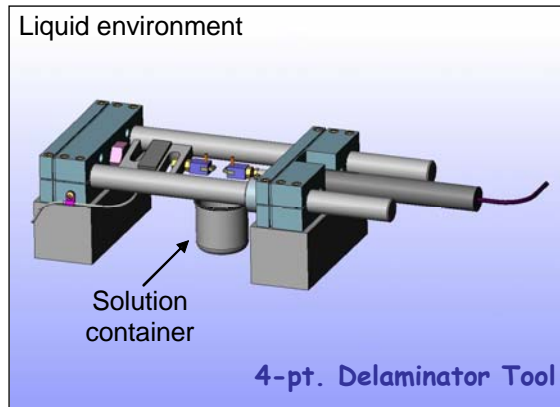
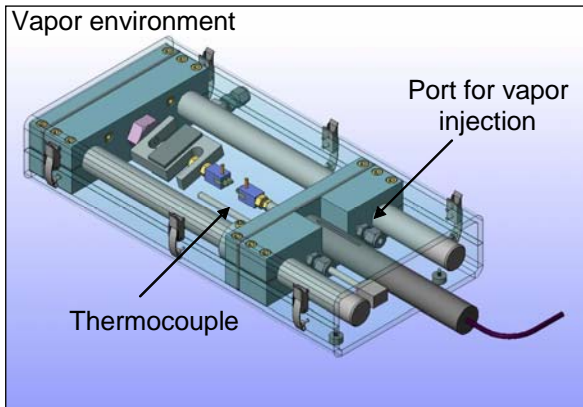
- Optimize resistance to cracking - glass composition, network and pore structure



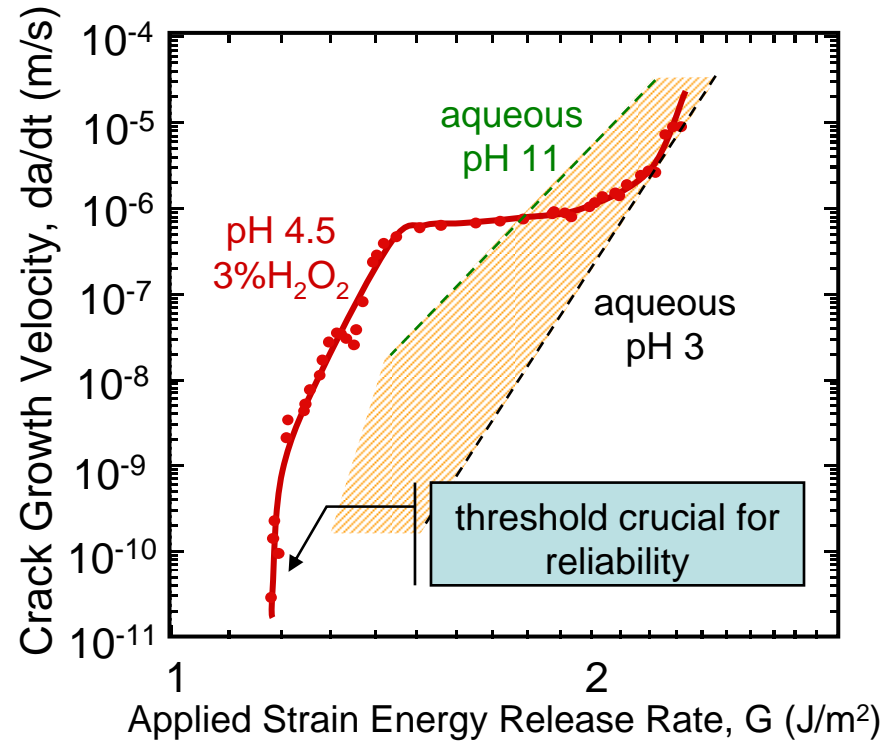
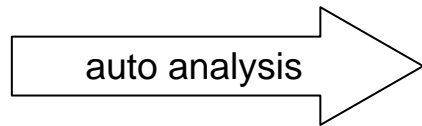
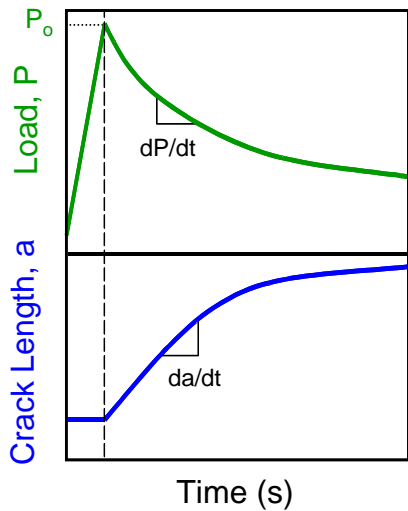
- Control evolution of defects during processing, packaging and service



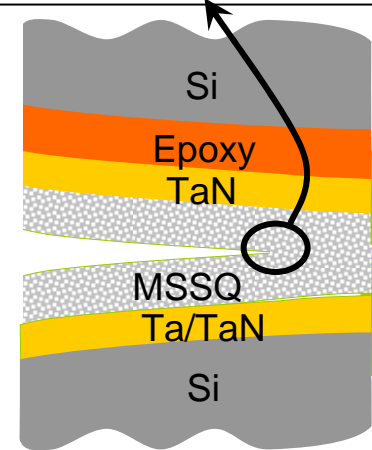
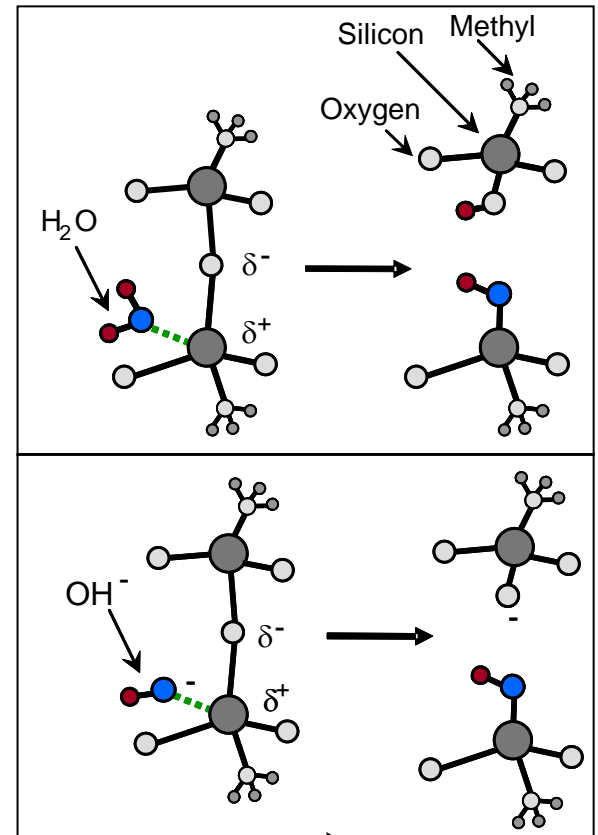
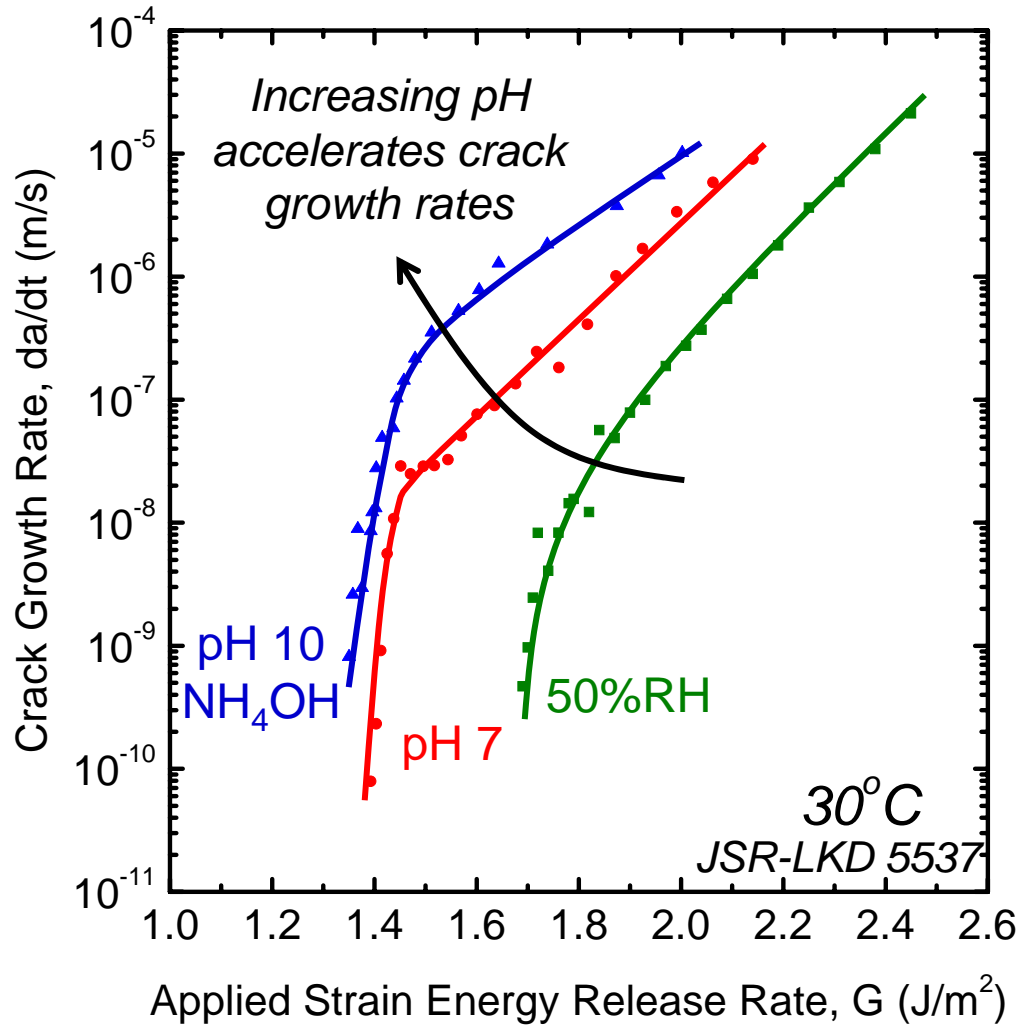
# Automated Crack Velocity Testing



## Load Relaxation Crack Growth Technique

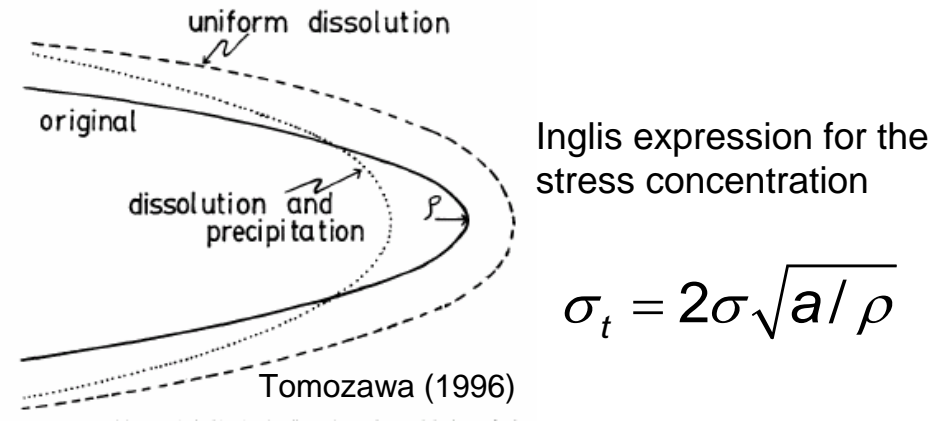
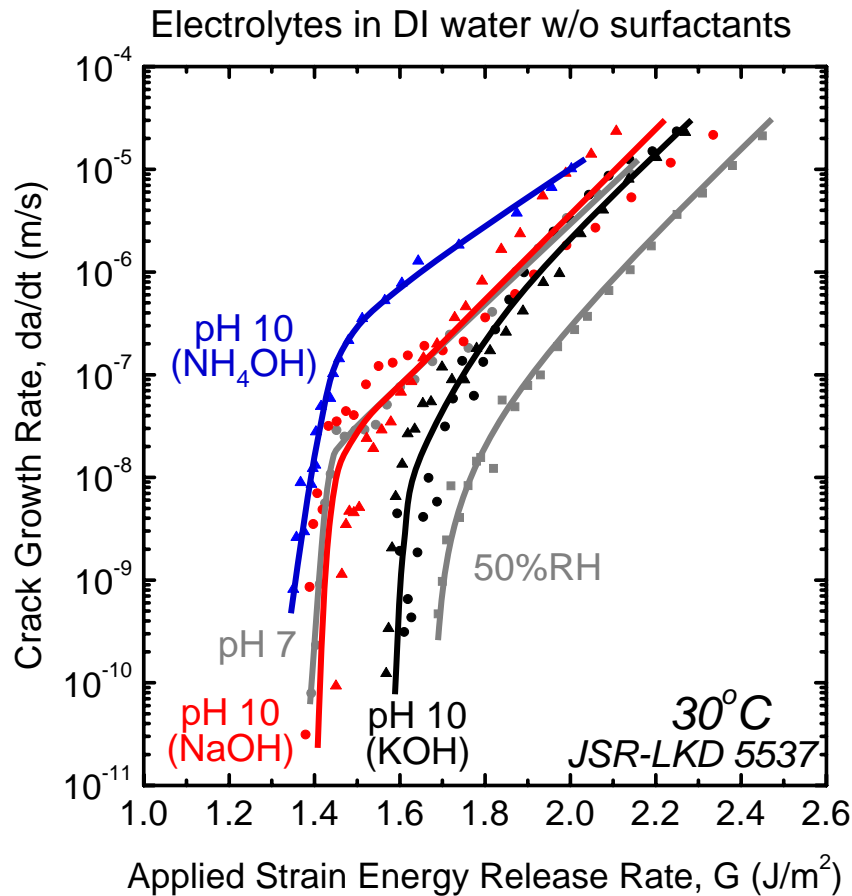


# Effects of Solution pH on Crack Growth



# Alkali metal ion + crack tip → decelerated crack growth by crack tip blunting

Crack tip gets blunted by dissolution of the silica backbone.



Silica gel dissolution in aqueous alkali metal hydroxides

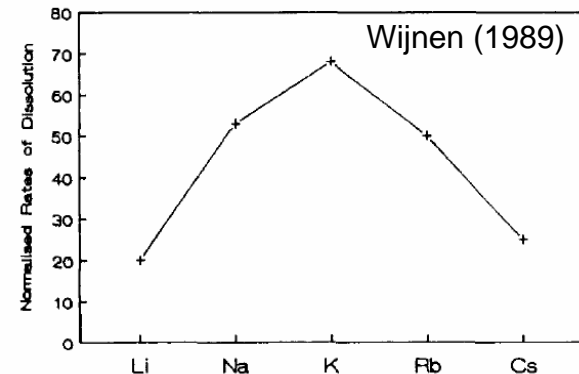


Fig. 5. Normalised rate of dissolution, obtained from <sup>29</sup>Si-NMR spectra, as a function of alkali metal hydroxide.

# Effects of Nonionic Surfactants on Defect Evolution during CMP

Surfactant additions critical for efficient CMP:

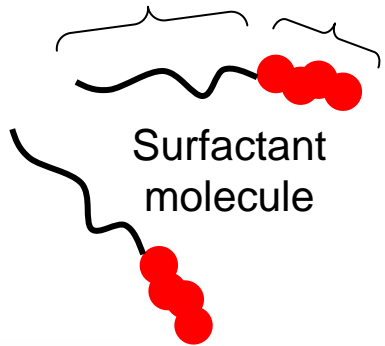
- enhances wetting of hydrophobic low-k dielectrics
- stabilizes CMP slurry
- optimized CMP removal rates, reduced dishing...

Effects of surfactant molecules on the defect evolution/crack growth are unknown!

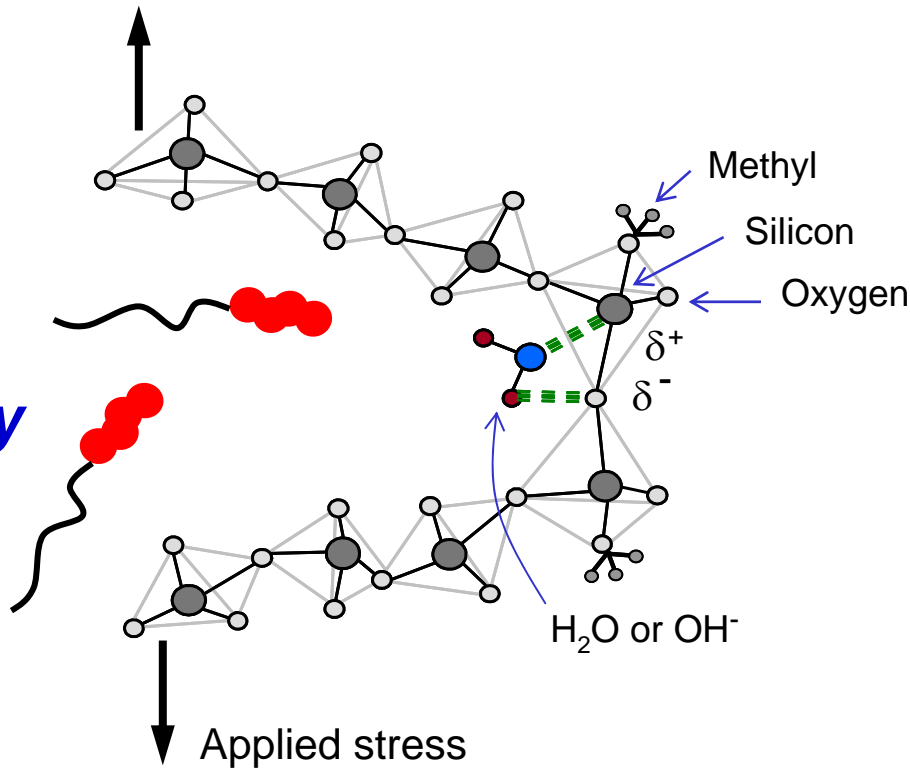
polyoxyethylene alkyl ether



Hydrophobic tail      Hydrophilic head

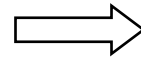
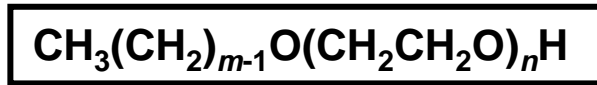


*CMP slurry*



# Nonionic Surfactants: Polyoxyethylene Alkyl Ethers

Monomeric surfactant



Hydrophobic hydrocarbon chain

Hydrophilic ethylene oxide (EO) chain

Commercial name	# of C, $m$	# of EO, $n$	HLB	Molecular weight (g/mol)	Molarity of 0.1wt% surfactant solution (M)
ETHALL DA-4	10	4	10.5	334	$2.99 \times 10^{-3}$
DA-6		6	12.4	423	$2.37 \times 10^{-3}$
DA-9		9	14.3	555	$1.80 \times 10^{-3}$
ETHALL LA-4	12	4	9.2	363	$2.76 \times 10^{-3}$
LA-7		7	12.2	495	$2.02 \times 10^{-3}$
LA-23		23	16.8	1200	$8.34 \times 10^{-4}$
LA-50		50	18.3	2389	$4.19 \times 10^{-4}$
BRIJ 76	18	10	12.4	711	$1.41 \times 10^{-3}$
78		20	15.3	1152	$8.68 \times 10^{-4}$
700		100	18.8	4676	$2.14 \times 10^{-4}$

Hydrophilic-Lipophilic Balance (HLB)

lipophilic (oil soluble)	1	20	hydrophilic (water soluble)
	←	→	

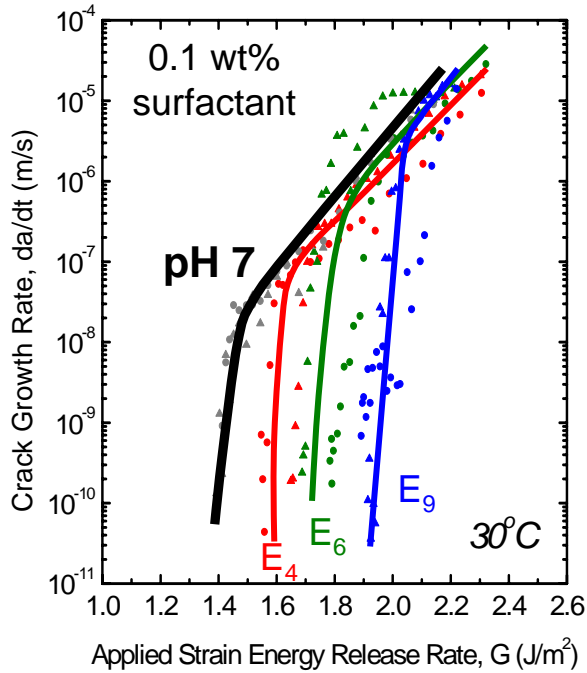
CMC @25 °C

BRIJ 76:  $4 \times 10^{-3}$  wt%

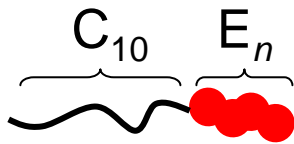
BRIJ 78:  $9.5 \times 10^{-4}$  wt%

# $C_m E_n$ Effects on Crack Growth Behavior (in pH 7 $\text{NH}_4\text{OH}$ )

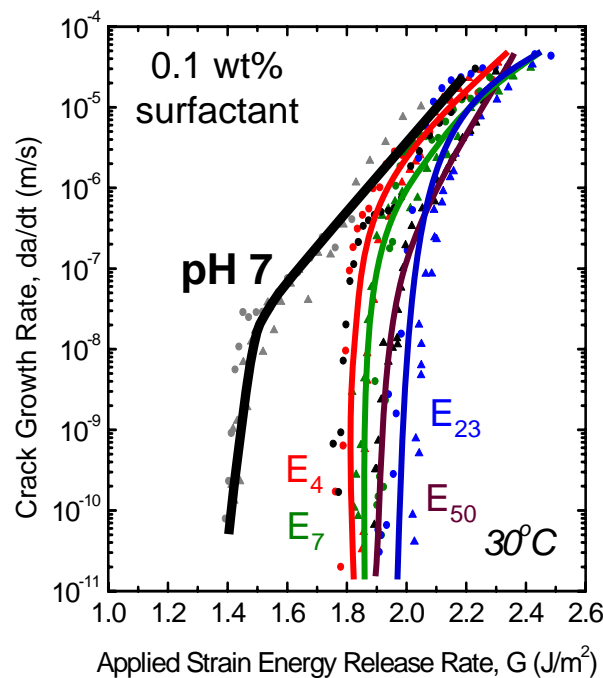
$C_{10} E_n$



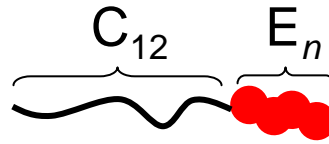
Marked effect on crack growth  
Sensitive to hydrophilic chain length



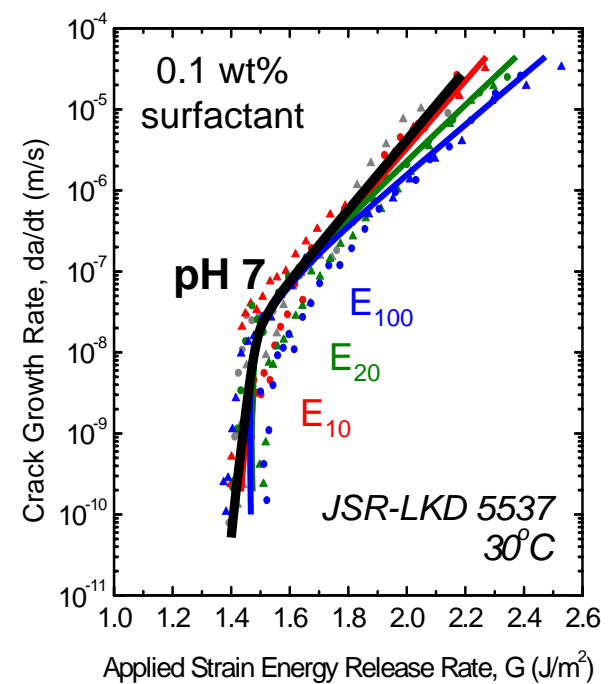
$C_{12} E_n$



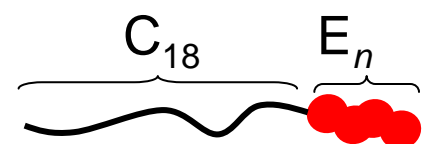
Marked effect on crack growth  
Insensitive to hydrophilic chain length



$C_{18} E_n$



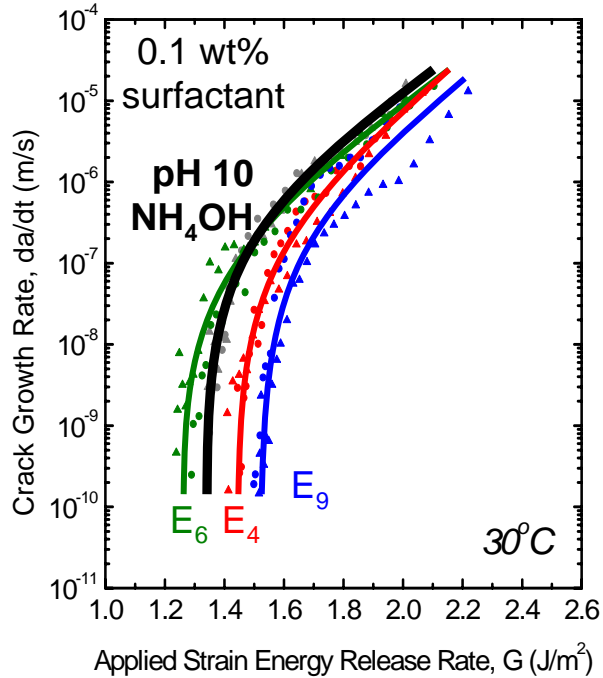
No effect of surfactant molecules



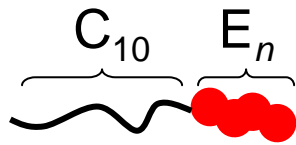


# $C_m E_n$ Effects on Crack Growth Behavior (in pH 10 $\text{NH}_4\text{OH}$ )

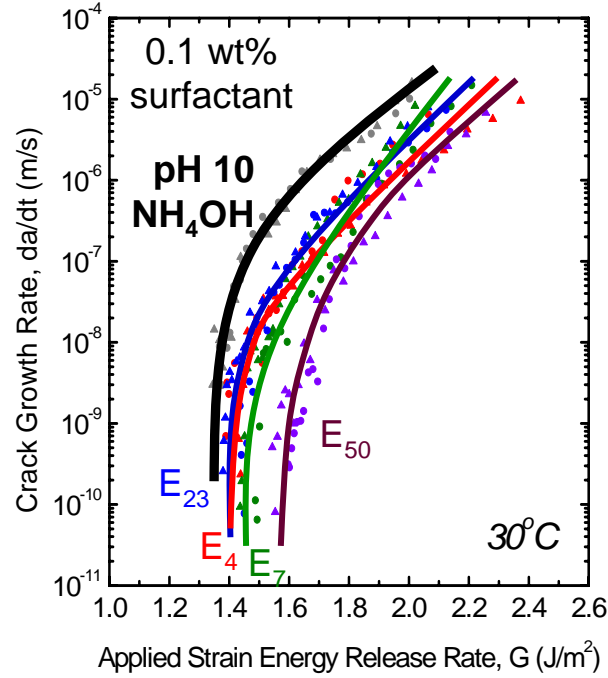
$C_{10} E_n$



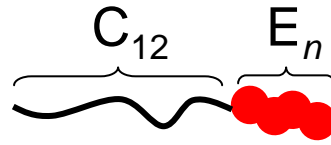
Little effect of surfactant molecules



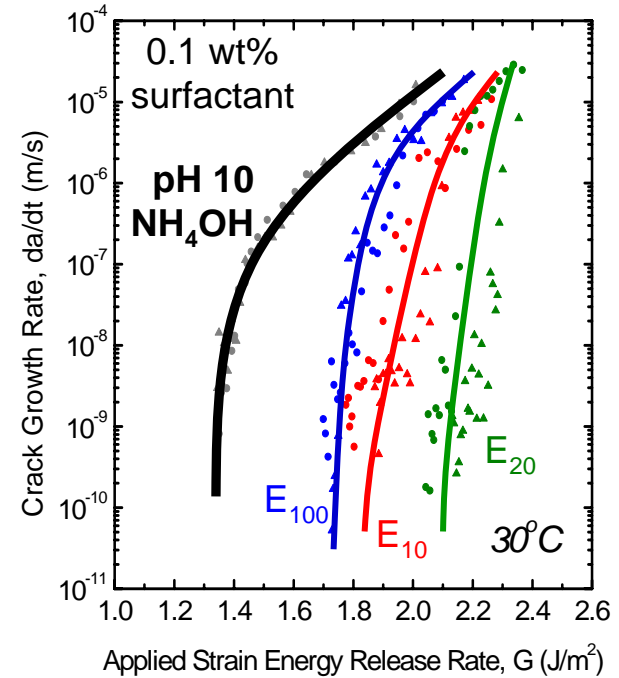
$C_{12} E_n$



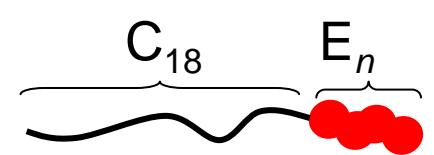
some effect on crack growth  
Insensitive to hydrophilic chain length



$C_{18} E_n$



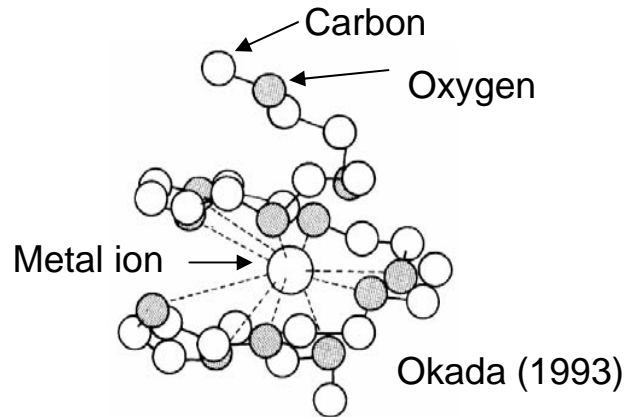
Marked effect on crack growth  
Sensitive to hydrophilic chain length



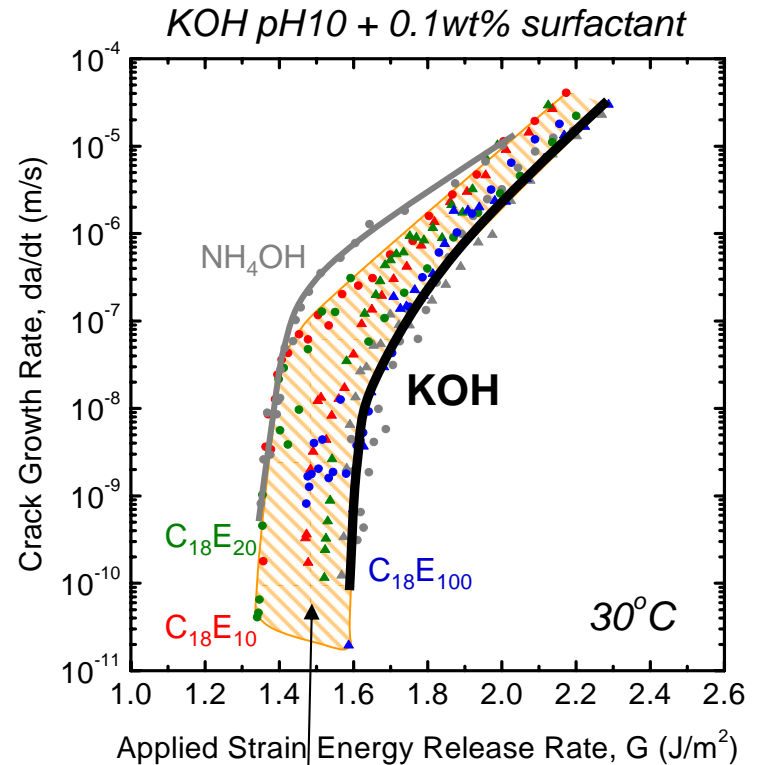
# $C_mE_n$ Effects on Crack Growth Behavior (in pH 10 KOH)

Alkali metal ion + EO  $\rightarrow$  Complexation

## EO of Polyoxyethylene Alkyl Ether



The EO chain locked by the cation, stabilized by electron-rich oxygen atoms, decreases mobility

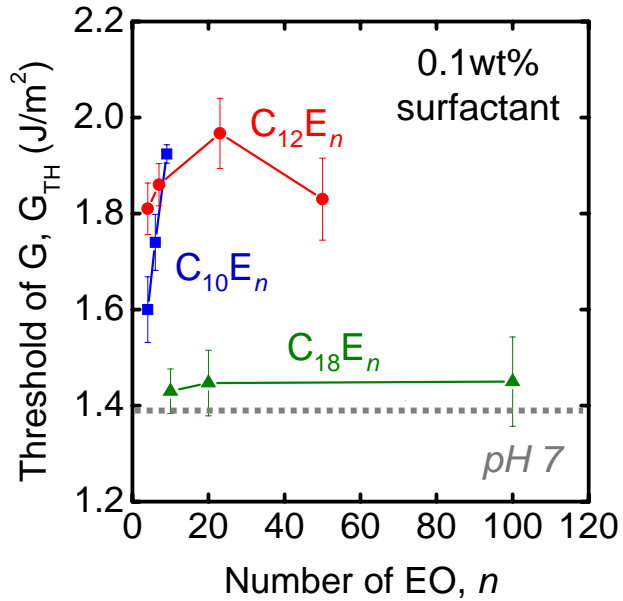


Crack tip blunting effects suppressed by shielding of potassium ion.

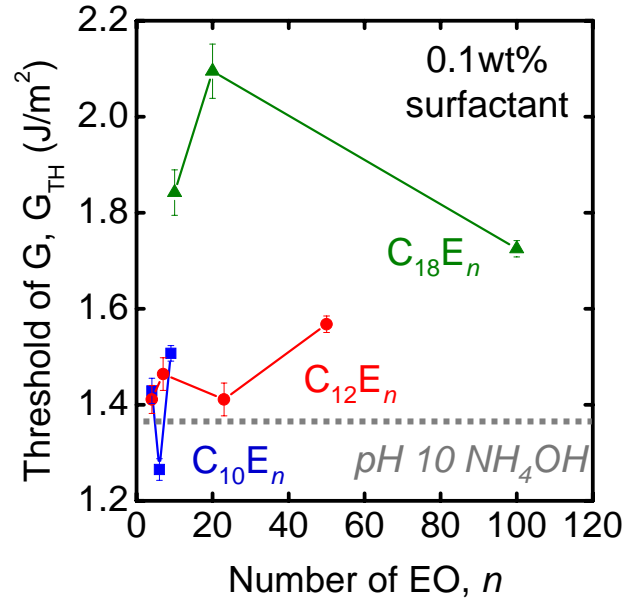
Also, complexation reduces hydrogen bonding sites  $\downarrow \rightarrow G_{\text{bridging}} \downarrow$

# Threshold Applied Strain Release Rate ( $C_m E_n$ )

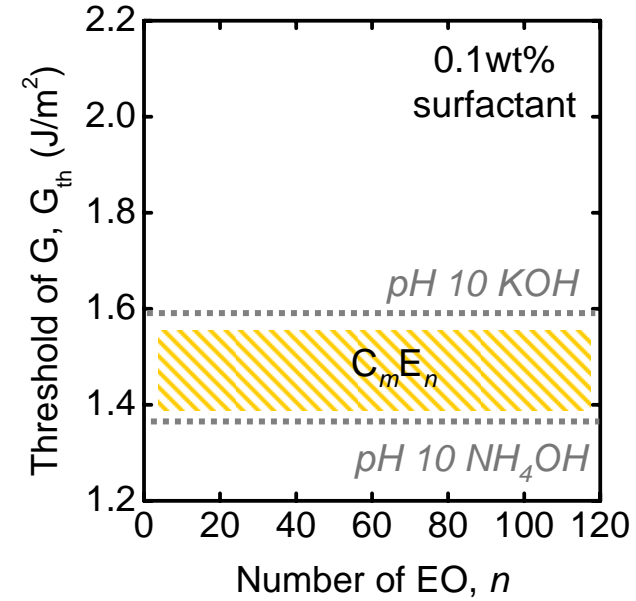
pH 7



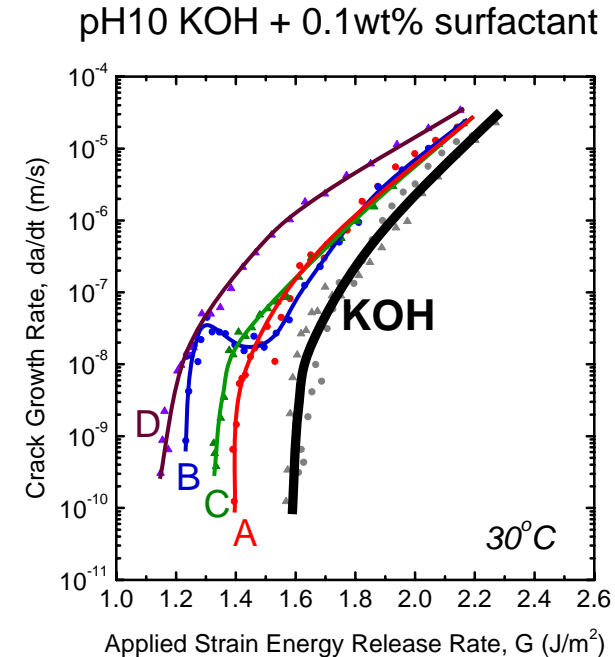
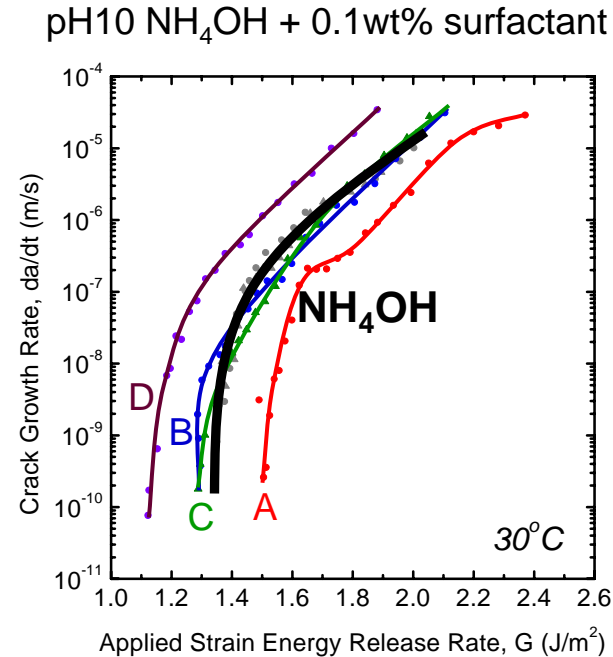
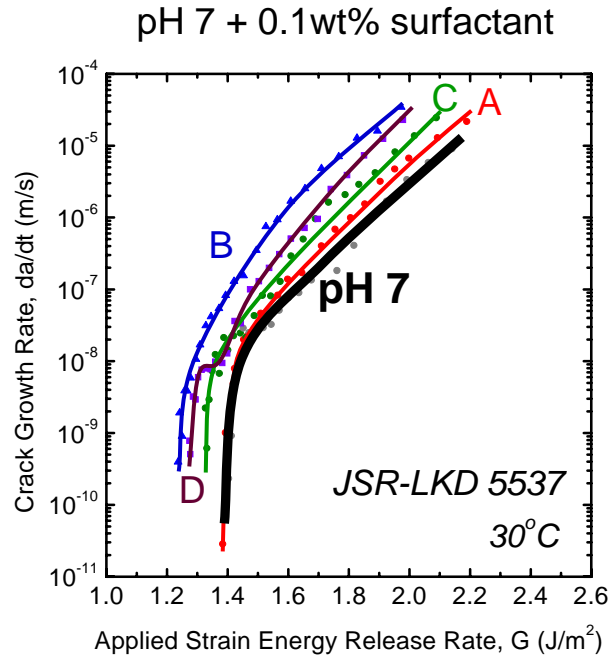
pH 10  $NH_4OH$



pH 10 KOH



# Nonionic Gemini (Dimeric) Surfactants Effects on Crack Growth Behavior



EO length: A < B < C < D

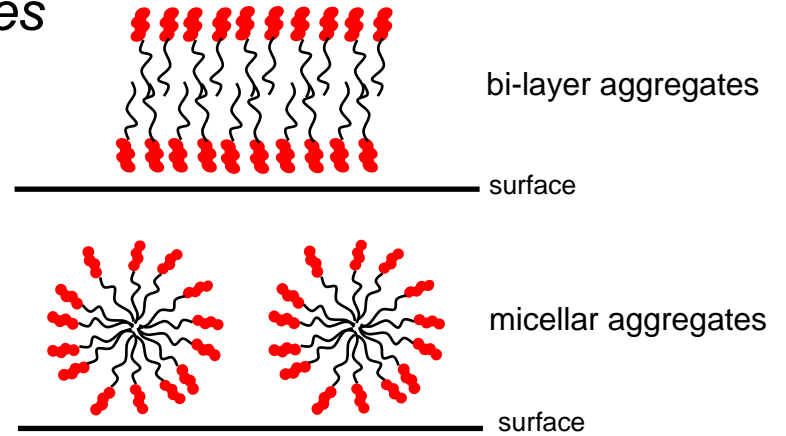
Low foaming (defoaming) and rapid surface wetting

→ accelerated crack growth

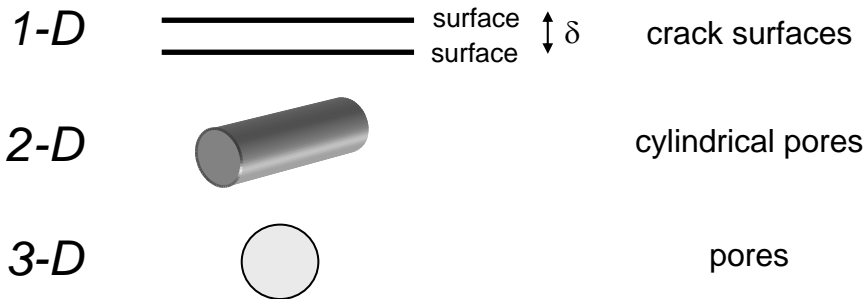
# Nonionic Surfactants Organization and Interaction with Surfaces

organization into aggregates depends on molecular type, concentration, temperature, pH, ionic content, surfaces, confinement....

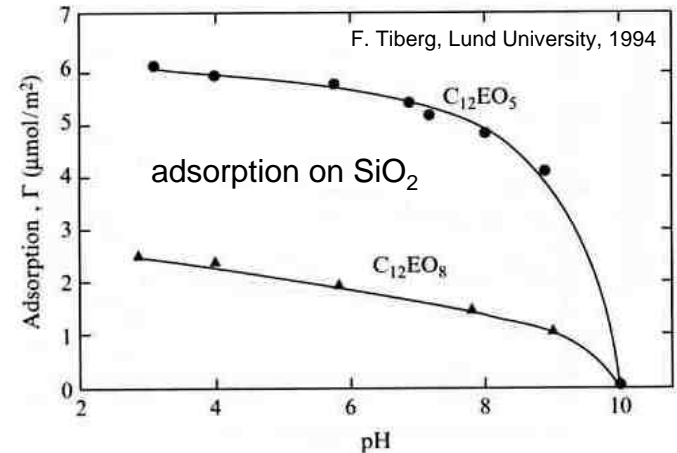
- $C_m E_n$ 
  - small  $n$  (large  $m$ )
  - high
- $SiO_2$  surface binding sites
- low
- large  $n$  (small  $m$ )



- confinement in cracks or pores



- pH effects

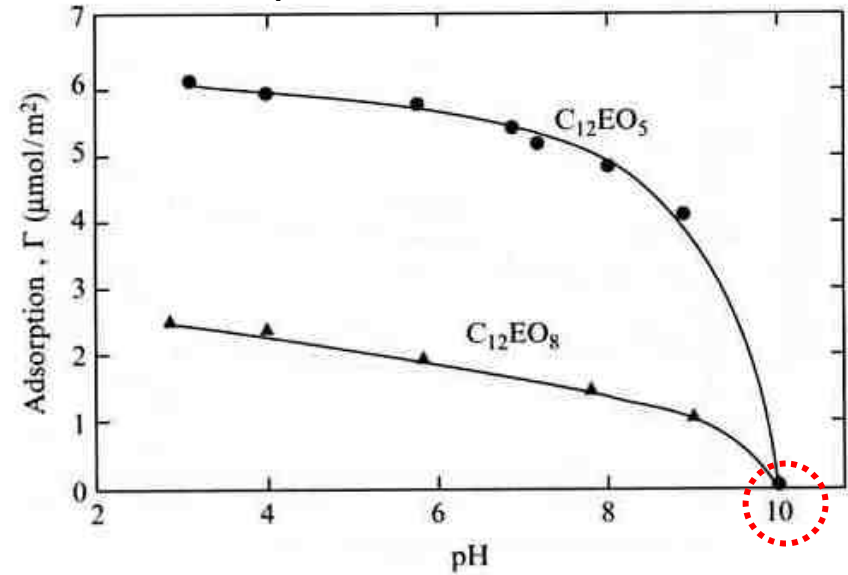


# Hydrophobic and Hydrophilic Interactions

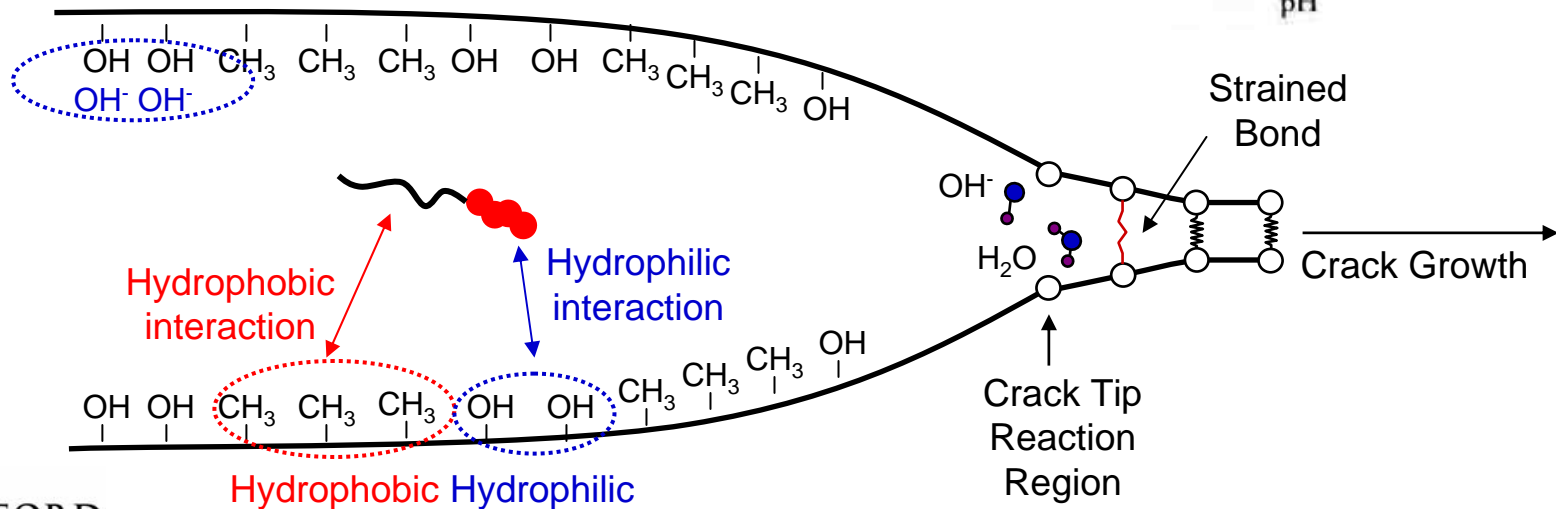
Hydroxyl ions from alkaline solution compete for adsorption sites and at pH levels above 10 all surfactants are displaced from the surface.

[F. Tiberg Ph.D. Thesis, Lund University. Sweden, 1994].

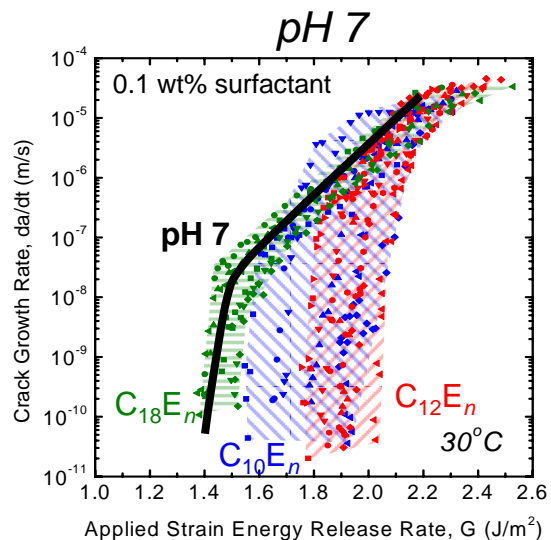
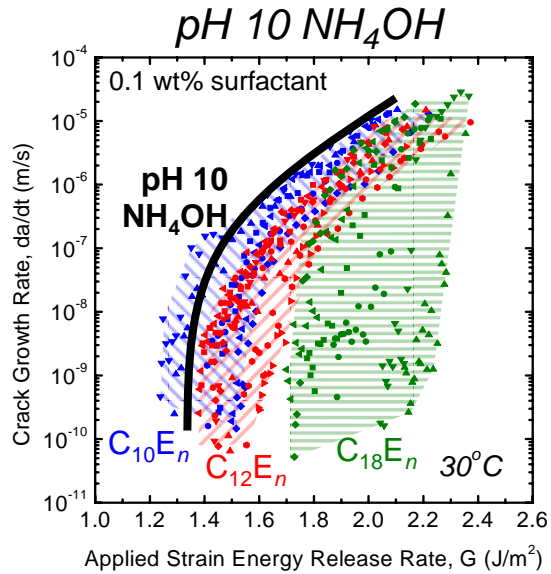
Adsorption on the silica surface



Competition for adsorption sites at high pH

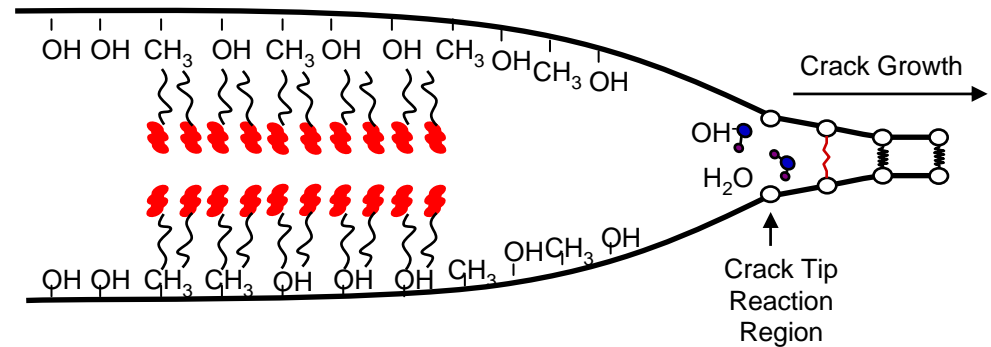
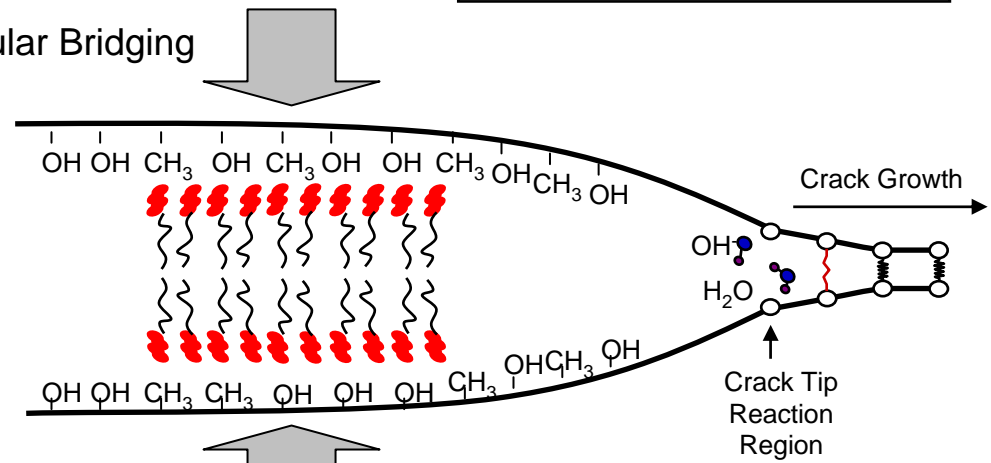


# Molecular Bridging in Aqueous Solution

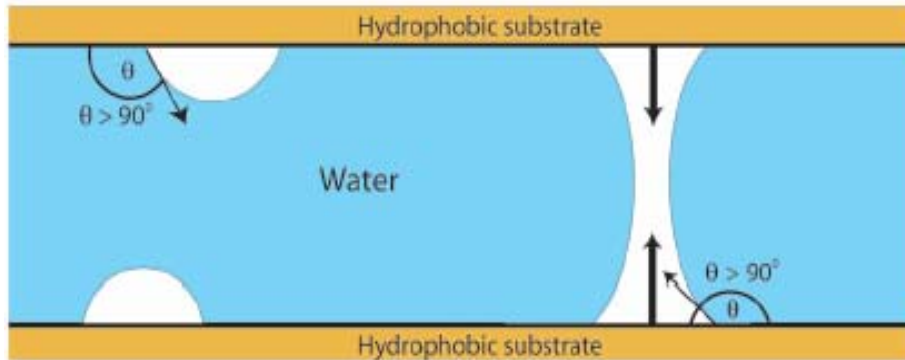


$$G_{tip} = G_{applied} - G_{bridging}$$

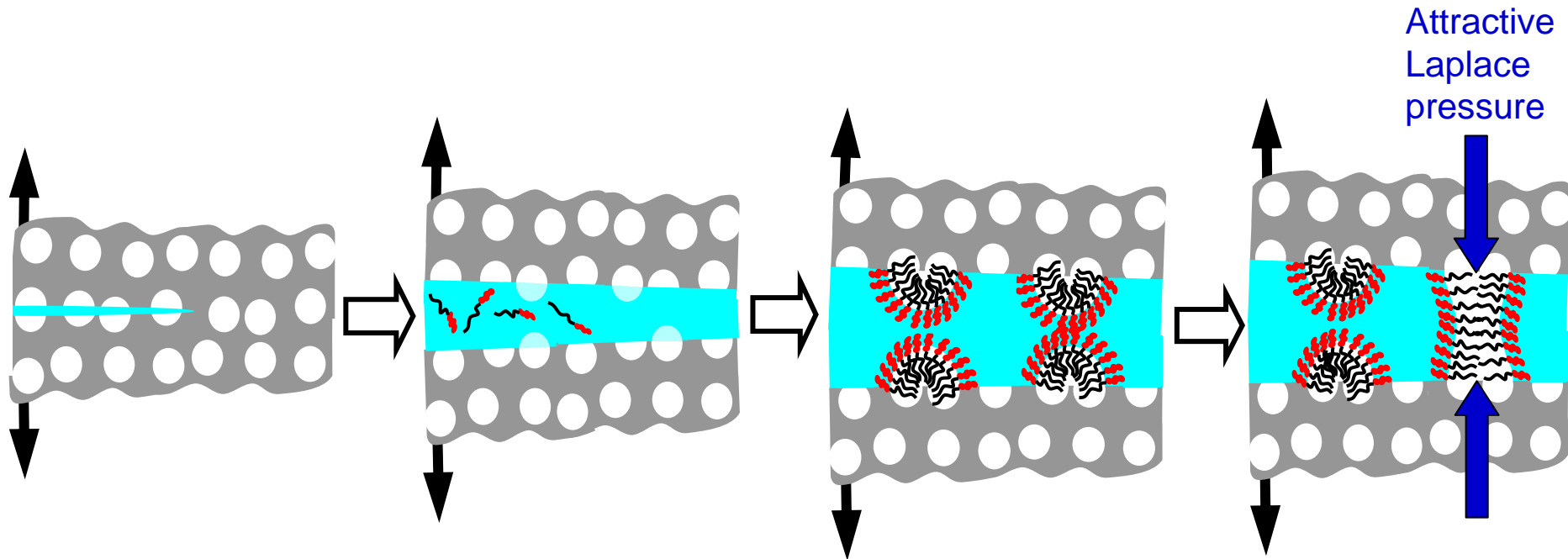
Molecular Bridging



# Surfactant-Enhanced Nanobubble Cavitation



When present on hydrophobic surfaces, nanobubbles can coalesce, leading to an attractive Laplace pressure. Adhesion  $\sim 1.0 \text{ J/m}^2$  was measured for  $D < 10 \text{ nm}$ . [Meyer, Rosenberg, and Israelachvili, 2006]





# Conclusions

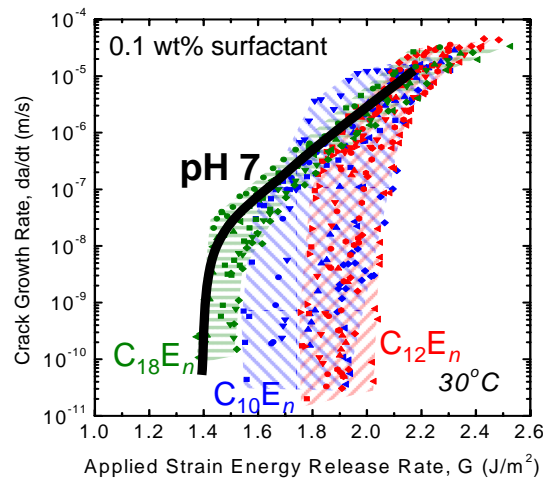
## Effects of surfactant additions on the defect evolution

Suppressed crack growth by bridging

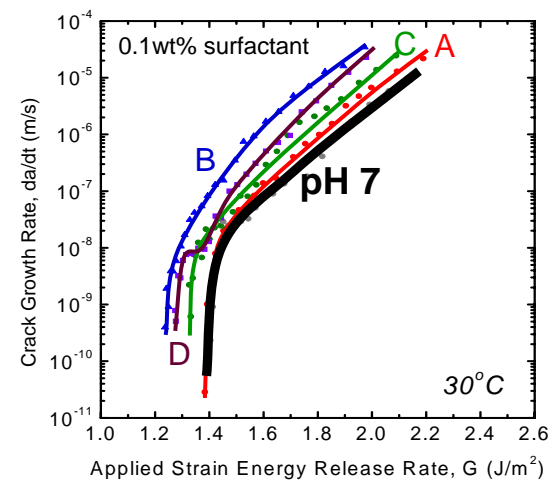


Accelerated crack growth by wetting

Monomeric surfactant:  
Polyoxyethylene alkyl ethers



Gemini (dimeric) surfactant



Building a new understanding of the effective CMP slurry formulations for the reliable integration of ultra-low-k materials at next technology nodes.

# Q & A